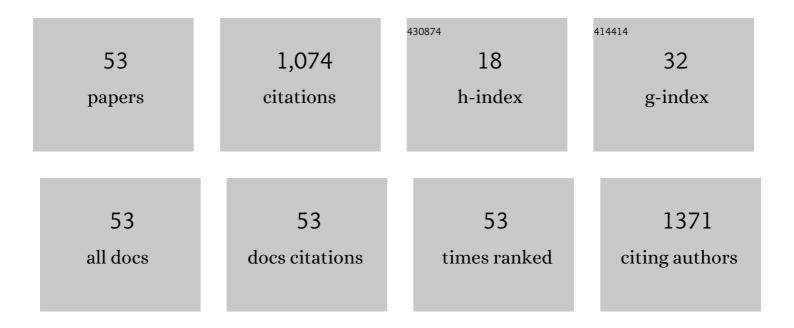
Kari Tapio Niemi

List of Publications by Year in descending order

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Κλαι Τλαιό Νιεμι

#	Article	IF	CITATIONS
1	Automated solvent vapor annealing with nanometer scale control of film swelling for block copolymer thin films. Soft Matter, 2019, 15, 7909-7917.	2.7	16
2	High molecular weight block copolymer lithography for nanofabrication of hard mask and photonic nanostructures. Journal of Colloid and Interface Science, 2019, 534, 420-429.	9.4	22
3	Morphology evolution of PS- b -PDMS block copolymer and its hierarchical directed self-assembly on block copolymer templates. Microelectronic Engineering, 2018, 192, 1-7.	2.4	12
4	All-Metal Broadband Optical Absorbers Based on Block Copolymer Nanolithography. ACS Applied Materials & Interfaces, 2018, 10, 42941-42947.	8.0	22
5	Metal/Polymer Back Reflectors with Diffraction Gratings for Light Trapping in III-V Solar Cells. , 2018, ,		0
6	Block Copolymer Patterning for Creating Porous Silicon Thin Films with Tunable Refractive Indices. ACS Applied Materials & Interfaces, 2017, 9, 31260-31265.	8.0	21
7	Effect of ZnO Addition and of Alpha Particle Irradiation on Various Properties of Er3+, Yb3+ Doped Phosphate Glasses. Applied Sciences (Switzerland), 2017, 7, 1094.	2.5	7
8	Site-controlled InAs quantum dot chains coupled to surface plasmons. Optica, 2016, 3, 139.	9.3	2
9	High Spectral Purity High-Power GaSb-Based DFB Laser Fabricated by Nanoimprint Lithography. IEEE Photonics Technology Letters, 2016, 28, 1233-1236.	2.5	17
10	Enhancement of second-harmonic generation from silicon nitride with gold gratings. Optics Express, 2015, 23, 30695.	3.4	5
11	Perfect magnetic mirror and simple perfect absorber in the visible spectrum. Physical Review B, 2015, 91, .	3.2	52
12	High quality InP nanopyramidal frusta on Si. CrystEngComm, 2014, 16, 4624-4632.	2.6	4
13	Mothâ€eye antireflection coating fabricated by nanoimprint lithography on 1 eV dilute nitride solar cell. Progress in Photovoltaics: Research and Applications, 2013, 21, 1158-1162.	8.1	38
14	Coating of gold nanoparticles made by pulsed laser ablation in liquids with silica shells by simultaneous chemical synthesis. Physical Chemistry Chemical Physics, 2013, 15, 3047-3051.	2.8	19
15	Single-step fabrication of luminescent GaAs nanocrystals by pulsed laser ablation in liquids. Optical Materials Express, 2012, 2, 799.	3.0	21
16	Selective area heteroepitaxy of InP nanopyramidal frusta on Si for nanophotonics. , 2012, , .		0
17	Hybrid waveguide-surface plasmon polariton modes in a guided-mode resonance grating. Optics Communications, 2012, 285, 4381-4386.	2.1	16
18	Selective area heteroepitaxy through nanoimprint lithography for large area InP on Si. Physica Status Solidi C: Current Topics in Solid State Physics, 2012, 9, 1610-1613.	0.8	3

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19	Infrared Pulsed Laser Deposition of Niobium Nitride Thin Films. IEEE Transactions on Applied Superconductivity, 2011, 21, 143-146.	1.7	14
20	Focusing effect of a graded index photonic crystal lens. Optics Communications, 2011, 284, 3140-3143.	2.1	26
21	Pulsed laser deposition of yttria-stabilized zirconium dioxide withÂaÂhigh repetition rate picosecond fiber laser. Applied Physics A: Materials Science and Processing, 2010, 98, 487-490.	2.3	8
22	Picosecond pulse laser ablation of yttria-stabilized zirconia fromÂkilohertz to megahertz repetition rates. Applied Physics A: Materials Science and Processing, 2010, 101, 735-738.	2.3	3
23	Photoconductivity of thin organic films. Applied Surface Science, 2010, 256, 3900-3905.	6.1	16
24	Large-area nanoperforated SiN membranes for optical and mechanical filtering. Microelectronic Engineering, 2010, 87, 1620-1622.	2.4	7
25	Aluminum doped zinc oxide films grown by atomic layer deposition for organic photovoltaic devices. Solar Energy Materials and Solar Cells, 2010, 94, 1379-1383.	6.2	78
26	Nanostructured broadband antireflection coatings on AlInP fabricated by nanoimprint lithography. Solar Energy Materials and Solar Cells, 2010, 94, 1845-1848.	6.2	75
27	Laterally-coupled distributed feedback InGaSb/GaSb diode lasers fabricated by nanoimprint lithography. Electronics Letters, 2010, 46, 1146.	1.0	6
28	Nanoperforated silicon membranes fabricated by UV-nanoimprint lithography, deep reactive ion etching and atomic layer deposition. Journal of Micromechanics and Microengineering, 2010, 20, 077001.	2.6	19
29	Broadband infrared mirror using guided-mode resonance in a subwavelength germanium grating. Optics Letters, 2010, 35, 2564.	3.3	19
30	Soft stamp ultraviolet-nanoimprint lithography for fabrication of laser diodes. Journal of Micro/ Nanolithography, MEMS, and MOEMS, 2009, 8, 033004.	0.9	11
31	Applications of UV-nanoimprint soft stamps in fabrication of single-frequency diode lasers. Microelectronic Engineering, 2009, 86, 321-324.	2.4	51
32	Soft stamp UV-nanoimprint lithography for fabrication of laser diodes. Proceedings of SPIE, 2009, , .	0.8	8
33	Inhomogeneities in the nonlinear tensorial responses of arrays of gold nanodots. New Journal of Physics, 2008, 10, 013001.	2.9	16
34	Narrow linewidth templates for nanoimprint lithography utilizing conformal deposition. Nanotechnology, 2008, 19, 015302.	2.6	10
35	Role of local fields and defects in the nonlinear response of metal nanostructures. Proceedings of SPIE, 2008, , .	0.8	0

Longitudinally single mode laser-diode fabricated with Nanoimprint Lithography. , 2008, , .

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37	Fabrication of surface reliefs on facets of singlemode optical fibres using nanoimprint lithography. Electronics Letters, 2007, 43, 150.	1.0	26
38	Topology-optimized and dispersion-tailored photonic crystal slow-light devices. Proceedings of SPIE, 2007, , .	0.8	2
39	Selective growth experiments on gallium arsenide (100) surfaces patterned using UV-nanoimprint lithography. Microelectronics Journal, 2006, 37, 1477-1480.	2.0	5
40	Optimization and applications of planar silicon-based photonic crystal devices. , 2005, , .		0
41	Effects of dispersion on nonlinearity measurement of optical fibers. Optical Fiber Technology, 2005, 11, 278-285.	2.7	12
42	Comprehensive FDTD modelling of photonic crystal waveguide components. Optics Express, 2004, 12, 234.	3.4	176
43	Polarization-mode dispersion of large mode-area photonic crystal fibers. Optics Communications, 2003, 226, 233-239.	2.1	34
44	Wavelength reference for optical telecommunications based on a temperature-tunable silicon etalon. Review of Scientific Instruments, 2003, 74, 3620-3623.	1.3	7
45	Device for frequency chirp measurements of optical transmitters in real time. Review of Scientific Instruments, 2002, 73, 1103-1107.	1.3	4
46	New method to improve the accuracy of group delay measurements using the phase-shift technique. Optics Communications, 2002, 204, 119-126.	2.1	22
47	Tunable silicon etalon for simultaneous spectral filtering and wavelength monitoring of a DWDM transmitter. IEEE Photonics Technology Letters, 2001, 13, 58-60.	2.5	19
48	Effect of optical filtering on pulses generated with a gain-switched DFB laser. Optics Communications, 2001, 192, 339-345.	2.1	4
49	Limitations of phase-shift method in measuring dense group delay ripple of fiber Bragg gratings. IEEE Photonics Technology Letters, 2001, 13, 1334-1336.	2.5	100
50	Scalability of a Metropolitan Bidirectional Multifiber WDM-Ring Network. Photonic Network Communications, 2001, 3, 349-362.	2.7	0
51	Temperature-tunable silicon-wafer etalon for frequency chirp measurements. Microwave and Optical Technology Letters, 1999, 20, 190-192.	1.4	8
52	Nanoimprint Lithography - Next Generation Nanopatterning Methods for Nanophotonics Fabrication. , 0, , .		9
53	Three-grating monolithic phase-mask for the single-order writing of large-period gratings. Journal of the European Optical Society-Rapid Publications, 0, 6, .	1.9	1